



The 9th CNS-Nanofabrication Summer School –(2017)



Center for
Nanoscale
Systems
Harvard University
FAS • SEAS

CNS Nanofabrication Team will continue offering summer tutorials on nanofabrication technologies in 2017. In these tutorial series, fundamentals of each nanofabrication technology will be introduced; operation principles, process tips/tricks will be discussed. All CNS users are eligible to attend.

<i>Jun 9</i>	Introduction of Nanofabrication	<i>JD Deng</i>
<i>Jun 16</i>	Photolithography	<i>Ameha/Guixiong</i>
<i>Jun 23</i>	E-beam Lithography (EBL)	<i>Yuan Lu</i>
<i>Jun 30</i>	Metrology for Nanofabrication	<i>Jason Tresback</i>
<i>July 7</i>	Reactive Ion Etch (RIE)	<i>Ling Xie</i>
<i>July 12</i>	Ion-beam etching(IBE) technology with SIMs	<i>IntlVac</i>
<i>July 14</i>	Advanced Plasma etching and Deposition	<i>Oxford Instrument</i>
<i>June 21</i>	Laser direct writing lithography	<i>Guixiong/ Heidelberg</i>
<i>July 28</i>	Chemical Vapor Deposition (CVD) and Physical Vapor Deposition (PVD)	<i>Philippe Ed Macomber</i>
<i>Aug 4</i>	Atomic Layer Deposition (ALD)	<i>Mac/Philippe</i>
<i>Aug 11</i>	Low-pressure CVD (LPCVD) Technology	<i>Tystar Inc.</i>
<i>Aug 18</i>	MEMS process and Packaging	<i>Guixiong Zhong</i>
<i>Aug 25</i>	Advanced SPM technology	<i>Antonio/ NearSpec</i>

10 μ m

WD = 5.3 mm

EHT = 5.00 kV

Mag = 1.45 K X

Width = 206.9 μ m

Signal A = SE2

Cycle Time = 10.1 Secs

Location and Time: 100 Geological Lecture Hall, 24 Oxford St., Cambridge MA, 02138, Friday, 12:00-1:30pm, Pizza lunch is available.

- The agenda may be changed according to staff's availability.

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